INTERNATIONAL STANDARD

ISO 3310-3

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Test sieves — Technical requirements and testing —

Part 3:

Test sieves of electroformed sheets

Tamis de contrôle — Exigences techniques et vérifications — Partie 3: Tamis de contrôle en feuilles électroformées



Foreword

ISO (the International Organization for Standardization) is a worldwide federation of national standards bodies (ISO member bodies). The work of preparing International Standards is normally carried out through ISO technical committees. Each member body interested in a subject for which a technical committee has been established has the right to be represented on that committee. International organizations, governmental and non-governmental, in liaison with ISO, also take part in the work. ISO collaborates closely with the International Electrotechnical Commission (IEC) on all matters of electrotechnical standardization.

Draft International Standards adopted by the technical committees are circulated to the member bodies for voting. Publication as an International Standard requires approval by at least 75 % of the member bodies casting a vote.

International Standard ISO 3310-3 was prepared by Technical Committee ISO/TC 24, Sieves, sieving and other sizing methods.

ISO 3310 consists of the following parts, under the general title *Test sieves — Technical requirements and testing*:

- Part 1: Test sieves of metal wire cloth
- Part 2: Test sieves of perforated metal plate
- Part 3: Test sieves of electroformed sheets

Annex A of this part of ISO 3310 is for information only.

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Introduction

Since the accuracy of test sieving depends on the dimensional accuracy of the test sieve openings, the consistency of size within very close tolerances that can be achieved for the openings of electroformed sheet makes them attractive for test sieving of very fine particulate material.

Test sieves of electroformed sheet must be handled with particular care as the very fine apertures are invisible to the unaided eye. Notes on cleaning these sieves before and after use are given in annex A.



Test sieves — Technical requirements and testing —

Part 3:

Test sieves of electroformed sheets

1 Scope

This part of ISO 3310 specifies the technical requirements and corresponding test methods for test sieves in which the sieving medium is a metal sheet with electrochemically formed apertures.

It applies to test sieves having round (circular) or square apertures ranging in size from 500 μm to 5 μm , in accordance with ISO 565.

2 Normative reference

The following standard contains provisions which, through reference in this text, constitute provisions of this part of ISO 3310. At the time of publication, the edition indicated was valid. All standards are subject to revision, and parties to agreements based on this part of ISO 3310 are encouraged to investigate the possibility of applying the most recent edition of the standard indicated below. Members of IEC and ISO maintain registers of currently valid International Standards.

ISO 565:1990, Test sieves — Metal wire cloth, perforated metal plate and electroformed sheet — Nominal sizes of openings.

3 Designation

Test sieves of electroformed sheet shall be designated by the shape of the apertures (round or square), the nominal size of apertures in micrometres (μ m) and the description "electroformed".

4 Electroformed sheet

4.1 General requirements

Electroformed sheet in test sieves shall be free from any irregularities such as production defects, creases, wrinkles or foreign matter in the sheet.

4.2 Arrangement of apertures

Round apertures shall be arranged with their centres at the apices of equilateral triangles (see figure 1); square apertures shall be arranged in line, with their mid-points at the vertices of squares (see figure 2).

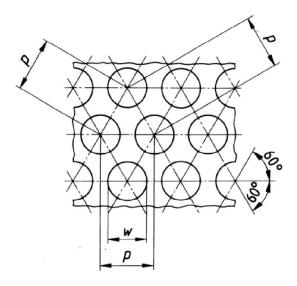


Figure 1 — Arrangement of round apertures

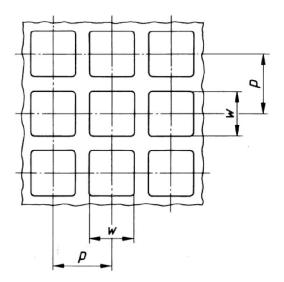


Figure 2 — Arrangement of square apertures

4.3 Dimensions

The nominal aperture sizes, preferred nominal pitches and preferred sheet thicknesses of electroformed sheet shall be as specified in table 1.

4.3.1 Tolerance on aperture size w

The average tolerance of all measured aperture sizes shall not exceed $\pm 2~\mu m$. This tolerance applies to the widths of the mid-sections of square apertures and to the diameter of round apertures, measured on the sieving side (i.e. it applies to the smallest aperture dimension; see figure 5).

4.3.2 Pitch p

The pitch sizes given in table 1, column 4, apply to either round or square apertures and shall be used by preference. Other pitches used shall be within the limits given in table 1, columns 5 and 6.

4.3.3 Sheet thickness e

The preferred sheet thicknesses given in table 1, column 7, apply to electroformed sheet with either round or square apertures, measured without sheet reinforcement, if any.

4.4 Test methods

Test 1 — General examination

View the sieving medium against a uniformly illuminated background. During this procedure turn the sieve slowly around an axis parallel to the aperture rows; this permits detection of unequal apertures.

If irregularities of aperture size are seen, the sieve is unacceptable.

Test 2 — Measurement of aperture size

Sieves which have passed test 1 shall be submitted to an examination of aperture size.

Check the apertures in nine measurement fields as shown in figure 3. In each field measure at least five apertures. Each aperture inspected shall comply with the tolerance stated in 4.3.1.

For the examination of aperture sizes above 32 μm a microscope fitted with a $\times 20$ objective and a filar micrometer eyepiece of 10 to 12,5 power should be used. The apparatus shall be capable of making measurements to an accuracy of $\pm 0,5~\mu m$. The magnification of the apparatus shall be verified against a calibrated stage micrometer certified to $\pm 0,5~\mu m$ for the 0,01 μm scale divisions and having not more than $\pm 0,5~\mu m$ accumulated error for the complete scale.

For the examination of aperture sizes of $32~\mu m$ and below the apparatus described above is not suitable. Measurement methods for this range of aperture sizes are under study.

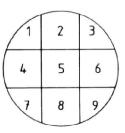


Figure 3 — Measurement fields for testing aperture size

Table 1- Nominal aperture sizes, pitch and sheet thickness

Dimensions in micrometres

Preferred she		Pitch		Nominal aperture sizes w		Nomi
thickness	inge of choice	Permissible ra	Preferred sizes	ntary sizes	Suppleme	Principal sizes
e	p_{min}	$p_{\sf max}$	p_{nom}	R 40/3	R 20	R 20/3
(7)	(6)	(5)	(4)	(3)	(2)	(1)
	530	710	620	500	500	500
50	475	645	560		450	
45	450 425	610 555	530 490	425	400	
	380	510	450	355	355	355
	335	480	395		315	
	320	440	380	300		
30	300	420	355		280	
	270	385	320	250	250	250
	250	340	275		224	
	240	320	270	212		
25	225	305	260		200	1
	200	270	240	180	180	180
 	180	255	210		160	
	170	230	200	150		
20 to 25	160	230	190		140	
	140	205	170	125	125	125
	135	205	155		112	
	130	205	150	106		
15 to 25	120	170	140	1	100	
	110	170	130	90	90	90
	100	170	115		80	
	95	140	110	75		
	90	140	105		71	
	90	140	95	63	63	63
	75	140	90	50	56	
40.4-05	70	100	85	53	50	
12 to 25	70 65	100 100	80 75	45	45	45
	60	90	70	45	40	40
	55	85	65	38	40	
	55	85	65		36	
						R'10
	50	85	60			32
	45	65	50			25
10 to 25	40	65	45			20
	35	65	40			16
	25	50	30			10
8 to 25	20	40	25			5

5 Test sieve frame

Test sieve frames shall be circular and made of stainless steel or any other material suitable for the samples to be sieved.

The dimensions and tolerances of test sieve frames shall comply with table 2, and in principle with figure 4.

NOTE 1 It is recognized that in countries where the 203 mm (8 in), 102 mm (4 in) and 76 mm (3 in) diameter test sieves have been established as a standard by long tradition, some considerable time may elapse before the transition can be made by users to employ the sieves specified in table 2.

Table 2 — Dimensions and tolerances of test sieve frames (see also figure 4)

Dimensions in millimetres

	e nominal es	Diameter of effective sieving surface	Approximate depth ¹⁾
D_1	D_2	y	H_1
(1)	(2)	(3)	(4)
75 ^{+0,3}	75 _{-0,3}	> 65	25
100 +0,4	100 0	> 90	25
200 +0,8	200 _0,8	> 185	25 or 50

1) Larger depths may be required for wet sieving.

6 Construction of test sieves

Depending on the production process, electroformed sheet has a cross-section in accordance with type A or type B as shown in figure 5. Sheet with

type A cross-section shall be fixed in the frame with the smaller width of the apertures uppermost to facilitate undersize particles clearing the apertures.

If reinforcement of the sheet is required, a supporting screen shall be bonded to the electroformed sheet, with the apertures in both the support and the sheet running in the same direction to prevent the formation of pockets in which particles may be trapped.

The frames shall be smoothly finished and they shall nest readily with other sieves, lids and receivers of the same nominal frame diameter.

The seal of the electroformed sheet with the frame shall be so constructed as to prevent lodging of material to be sieved.

7 Marking of test sieves

A metal label permanently attached to the frame shall give the following information:

- a) the shape of the aperture, by indicating a circle or a square as appropriate;
- b) the nominal aperture size;
- a reference to the standard(s) with which the test sieve is claimed to comply;
- d) the material of the sheet and of the frame;
- e) the name of the party (manufacturer or vendor) that is responsible for the sieve;
- f) the manufacturer's identification number.

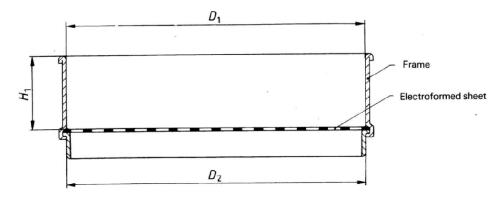
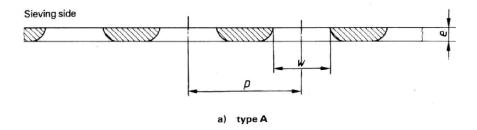


Figure 4 — Cross-section of test sieve with electroformed sheet



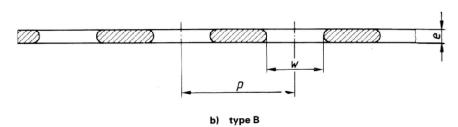


Figure 5 - Cross-section of electroformed sheet (diagrammatic)

Annex A (informative)

Care of test sieves of electroformed sheet

Test sieves of electroformed sheet shall be handled with great care to prevent their damage. Unless otherwise recommended by the manufacturer, the sieves shall be cleaned by immersing them vertically in a suitable liquid, e.g. alcohol or deionized water with or without a trace of non-corrosive surfactant, in an ultrasonic bath for 15 s to 20 s at a frequency of not less than 40 kHz and a power input not exceeding 40 W. They shall then be rinsed in

clean liquid and dried at a temperature not exceeding 80 °C.

Electroformed sheet should not be cleaned with a brush or by means of compressed air.

Test sieves with electroformed sheet should be inspected as detailed in 4.4 at regular intervals for compliance with this part of ISO 3310.





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Descriptors: sieve analysis, grain size analysis, test equipment, sieves, sizing screens, sieve plates, specifications, dimensions, tests, marking.

Price based on 6 pages